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PATENT
29925/37976

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Dong-su Park and
Kwang-seok Jeon

Serial No.: 10/021,322

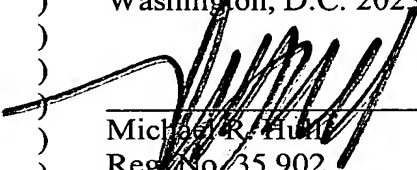
Filed: December 12, 2001

For: Method for Manufacturing
Tantalum Oxy Nitride Capacitors

Group Art Unit: 3723

Examiner: To be assigned

) I hereby certify that this paper and
) the documents referred to as
) enclosed therewith are being
) deposited with the United States
) Postal Service as first class mail,
) postage prepaid, on April 4, 2002,
) in an envelope addressed to
) Commissioner for Patents,
) Washington, D.C. 20231.

)
) 
) Michael R. Hunt
) Reg. No. 35,902
) Attorney for Applicants
)

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, D.C. 20231

Sir:

The patents listed on the enclosed PTO/SB/08 are submitted pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98. Copies of the patents are enclosed as necessary.

This information disclosure statement is being filed, to the best of the undersigned's knowledge, before the mailing date of a first office action on the merits. In accordance with 37 C.F.R. § 1.97(b), no certification or fee is required.

The Commissioner is authorized to charge any deficiency required by this paper, or credit any overpayment, to Deposit Account No. 13-2855.

Respectfully submitted,

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April 4, 2002

By:


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